

# Studies on impurities and F-radicals production in gaseous detectors operated with Freon based gas mixtures at LHC Experiments

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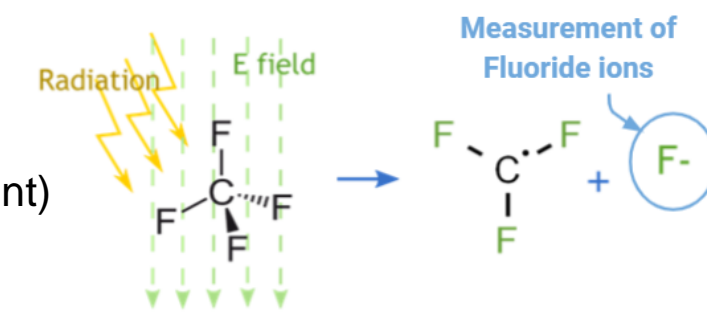


## Operation of gaseous detectors with Freon gases

Freon gases are used Gaseous detectors @LHC Experiments

- CF<sub>4</sub>: Wire Chambers, Gas Electron Multipliers (GEM)
- C<sub>2</sub>H<sub>2</sub>F<sub>4</sub> (R134a), SF<sub>6</sub>: Resistive Plate Chambers

Freon gases + Electric Field + Radiation  
= **Gas molecules break up**



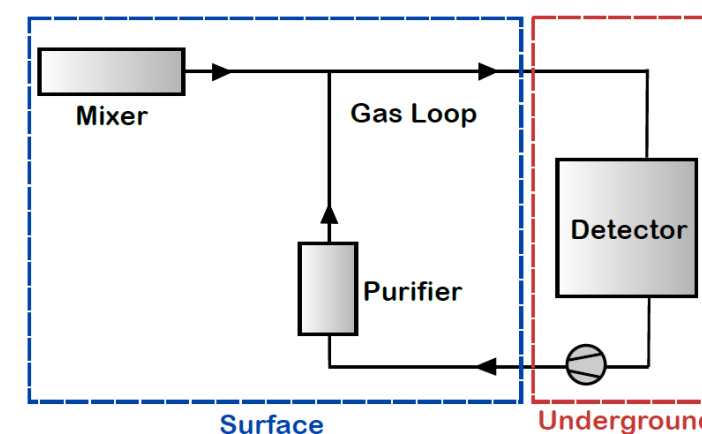
- Products are highly reactive
- Polymerized deposits (Hydrofluoric Acid if H<sub>2</sub>O present)
  - Etching compounds

Impurities production depends on many different operational factors:

type of Freon gas, gas mixture composition, gas flow rate, electric field in detector volume, irradiation rate..

## Operation with gas recirculation:

- Gas Mixture not sent to exhaust, re-injected in the gas system
- Lower GHG emission + gas cost
- Impurities produced in gas system or chamber can accumulate
- Purifier module designed for O<sub>2</sub>/H<sub>2</sub>O removal
- What is the action of Purifier on Fluoride impurities?



## Measurement of Fluoride Impurities

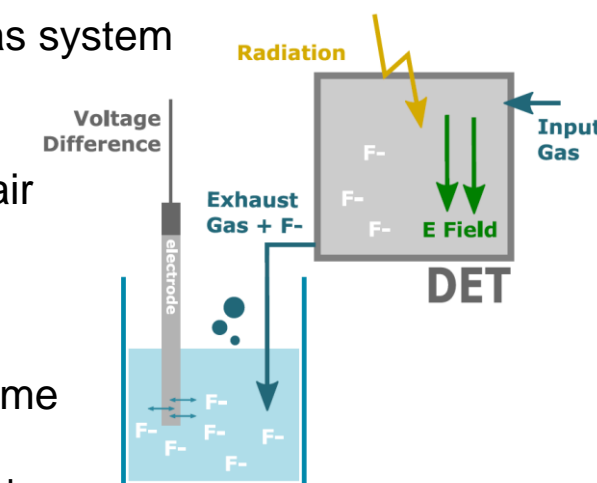
Fluoride impurities production quantified with measurement of Fluoride ion (F<sup>-</sup>)

### Ion Selective Electrode (ISE) Station

- Specific electrode for Fluoride in solution
- Sample solution with TISAB II to stabilize response

### Measurement:

- Gas sample from detector exhaust/gas system bubbled into sample solution
- Fluoride ion released in sample, other mixture component exhaust to air
- Fluoride ion interacts with electrode, voltage difference is produced
- Electrode voltage is proportional to Fluoride concentration in sample volume

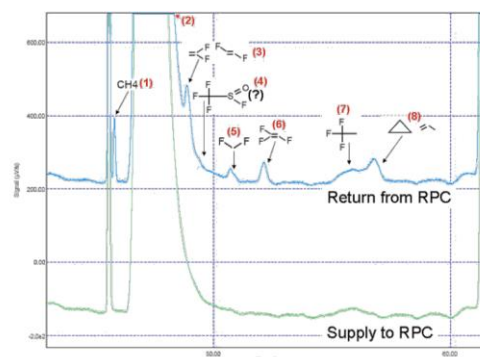


\*Fluoride ion concentration measured for sample solution volume, not detector/gas system volume

## Resistive Plate Chambers with R134a and HFO

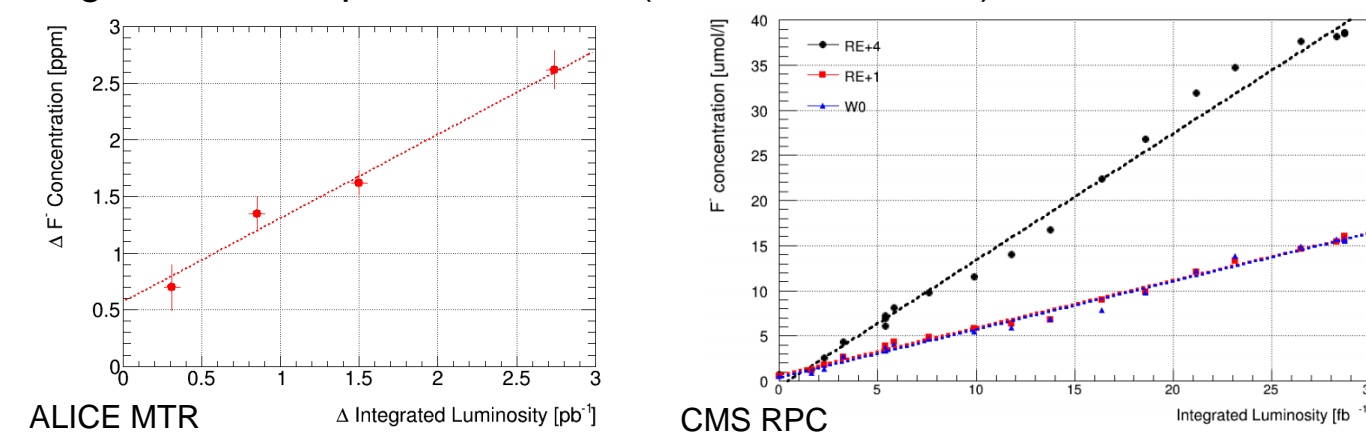
### Impurities Production in RPCs with R134a Mixture @LHC

- Impurities produced in RPCs operated with R134a-based mixture in high-rate radiation environment (R134a/iC<sub>4</sub>H<sub>10</sub>/SF<sub>6</sub> + RH40%)
- Impurities quantified with F<sup>-</sup> measurement
- F<sup>-</sup> + H<sub>2</sub>O → HydroFluoric Acid
- HF can significantly damage chambers
- Test in RPCs of CMS and ALICE during Run2
- Sampling points in various detector sections
- Continuous sampling of return gas 24/7, electrode measurements twice a week



### Results:

- Fluoride accumulation increase linearly with LHC Integrated Luminosity
- Detectors in regions more exposed to radiation show a higher Fluoride production rate (CMS RPC, RE+4)

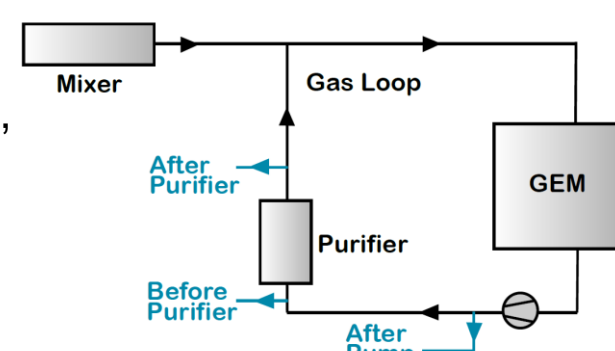


## Triple-GEMs with CF<sub>4</sub>

Triple-GEMs can be operated with CF<sub>4</sub> to improve time resolution  
Standard mixture composition is Ar/CO<sub>2</sub>/CF<sub>4</sub> in fractions 45/15/40

### Fluoride production in Triple-GEMs @LHCb – Run2

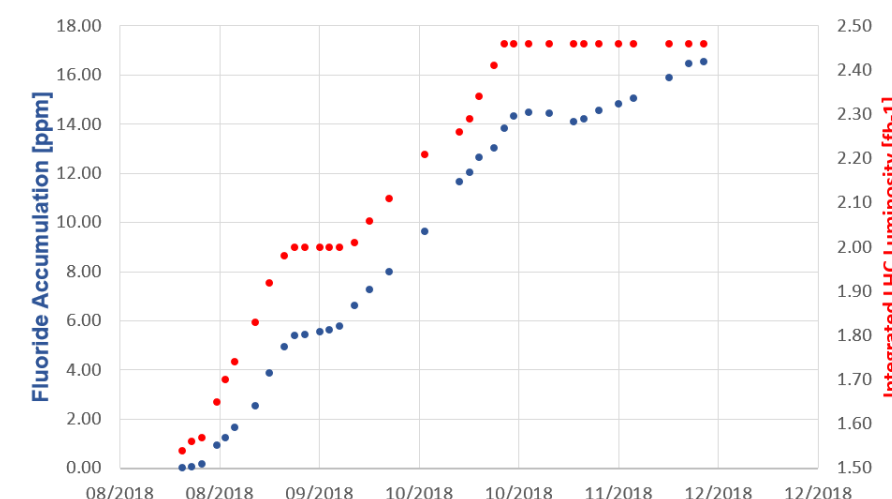
- Fluoride measurement in sampling point at the common return lines, sum of Fluoride produced in all operating chambers
- Sampling before and after the Purifier module
- Continuous sampling of return gas 24/7, electrode measurements twice a week



### Results:

Before purifier sample shows *proportionality of Fluoride accumulation and LHC Integrated Luminosity*

Flat periods = technical stops  
No LHC Luminosity, no Fluoride production

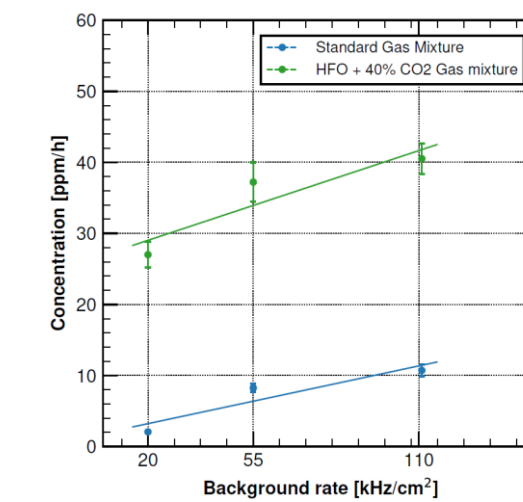


### Fluoride Production in RPCs with HFO Mixture @GIF++

- HFO possible candidate for RPCs eco-friendly gas mixture (HFO/C<sub>2</sub>H<sub>2</sub>F<sub>4</sub>/CO<sub>2</sub>/iC<sub>4</sub>H<sub>10</sub>/SF<sub>6</sub> 27.25/27.25/40/4.5/1)
- RPCs irradiated with <sup>137</sup>Cs source (14 TBq, γ ~ 0.1 MHz/cm<sup>2</sup>)
- Fluoride sampled at chambers exhaust

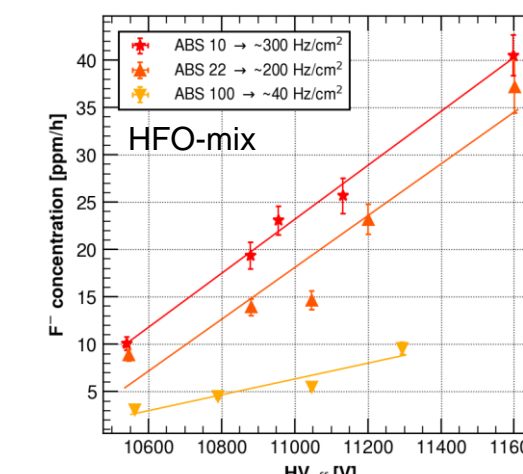
### HFO-mix vs Standard mix:

- Operation with HFO-mixture yields to Fluoride production rate ~4 times higher than operation with Standard mixture
- HFO break up rate ~ 10 times higher than R134a under same γ irradiation



### HFO-mix Fluoride production:

- HV scan with different irradiation rates
- Fluoride concentration linear with HV increase ~ detector current
- Fluoride production rate increases with the increase of radiation rate



### Fluoride production characterization @GIF++

- Fluoride sampling at chambers exhaust in different conditions
- Triple-GEMs irradiated with <sup>137</sup>Cs (14 TBq, γ ~ 60 MHz/cm<sup>2</sup>)

### Results:

#### CF<sub>4</sub> concentration

- Fluoride stable up to 50% CF<sub>4</sub>
- <10% increase for higher CF<sub>4</sub>
- F<sup>-</sup> does not strongly depend on CF<sub>4</sub> content in gas mixture

#### Input flow rate

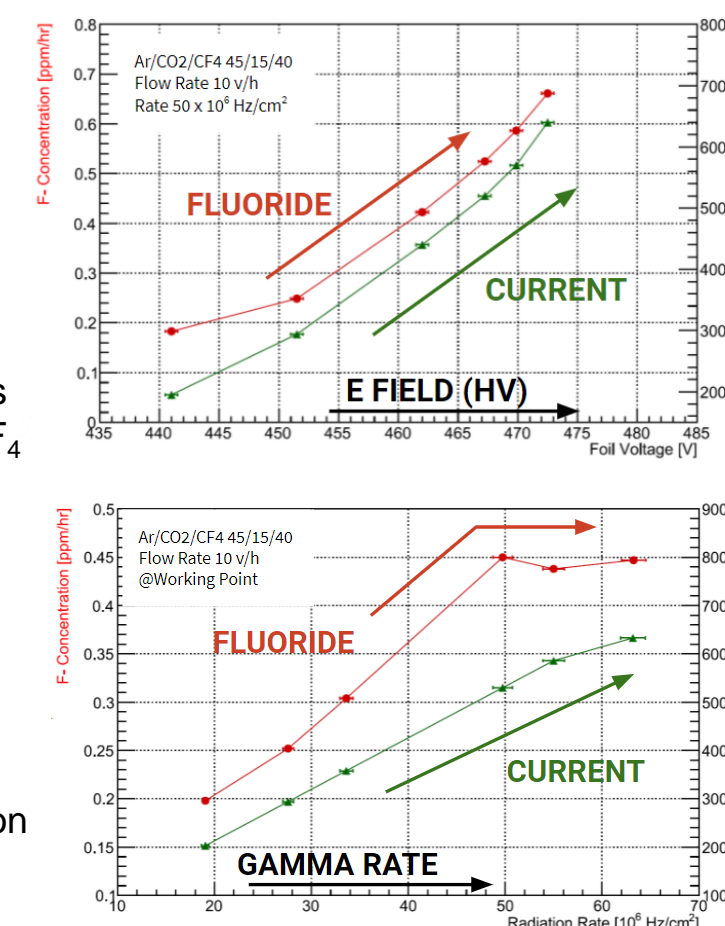
- Lower Fluoride for higher flow rates
- High flows allow faster transit of CF<sub>4</sub>

#### Electric field

- Higher E field, Fluoride increase
- Bigger electron avalanches, higher amplification gain ~ charge density

#### Radiation rate

- Current increase, Fluoride saturation
- More avalanches but same amplification gain, less CF<sub>4</sub> broken



## Fluoride Impurities with Gas Recirculation

Several gas detector systems at LHC experiments are operated with gas recirculation:

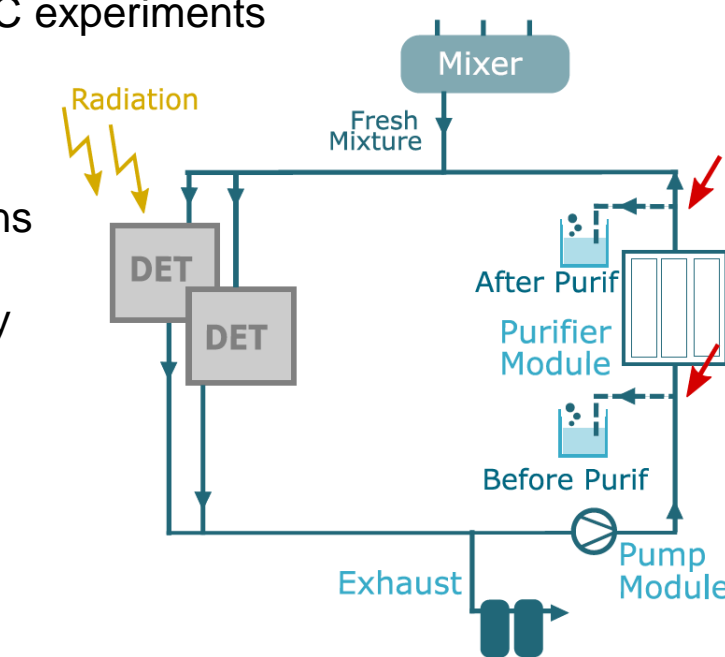
### Pros

- Reduced operational costs
- Lower Greenhouse Gas emissions

### Cons

- Compromised gas mixture quality
- Accumulation of impurities (N<sub>2</sub>, O<sub>2</sub>, H<sub>2</sub>O, Fluoride)

Standard Purifier module allows H<sub>2</sub>O and O<sub>2</sub> removal



Purifier effect on Fluoride tested in LHC Gas Systems (CMS RPC, ALICE MTR, LHCb GEM) and @GIF++

- Sampling points in gas recirculating systems located before and after Purifier module, continuous sampling during LHC Run / chambers irradiation

Fluoride accumulation measured before Purifier

**No accumulation in the sampling point after Purifier module for all the gas mixtures/detectors/gas systems tested**

Purifier module traps Fluoride, gas mixture can be safely re-injected

## Conclusions

Fluoride impurities are produced in gaseous detectors volume when operated with Freon gases in high-rate radiation environment

### Resistive Plate Chambers

- Operated with R134a in LHC Run2 (ALICE/CMS)**  
Fluoride production linear with Integrated Luminosity  
Sections exposed to higher radiation show higher impurity production
- Operated with HFO @ GIF++**  
Fluoride linear with RPCs detector current  
For equal detector current, more Fluoride produced with higher irradiation rate  
Operation with HFO-mix produces ~ 4 times more Fluoride than Standard mixture (break up HFO/R134a ~ 10)

### Triple-GEMs

- Operated with CF<sub>4</sub> in LHC Run2 (LHCb)**  
Fluoride production follows Integrated Luminosity  
No accumulation during stops of LHC activity
- Operated with CF<sub>4</sub> @ GIF++**  
Various operational factors influence Fluoride production  
Higher gas flows help decreasing impurity accumulation  
Increase of electric field and radiation both yield to higher production

### Fluoride impurities with Gas Recirculation

- Standard LHC Purifier module guarantees safe operation
- Fluoride is trapped: no accumulation with gas recirculation